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648.42568VX1

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: G. MIYA et al

EXPEDITED PROCEDURE

Serial No.: 10/779,742

BOX AF

Filed: February 18, 2004

For: Plasma Processing Method

Art Unit: 1763

Examiner: R. Kackar

**AMENDMENT AFTER FINAL REJECTION**

Mail Stop: Box AF Amendment (No Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

September 2, 2005

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated June 2, 2005 and in light of the interview conducted August 23, 2005 and subsequent telephone discussion. The amendments are listed below and set forth on the following pages.

Amendments to the Claims; and

Remarks are included following the amendments.